



Polymer Based MEMS and Microfabrication

Guest Editor:

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Message from the Guest Editor

Dear colleagues,

The use of polymers in microfabrication has become increasingly important, with applications ranging from microfluidic systems, neural probes, microrobotics and biomimetic materials all benefiting from the unique manufacturing options and material properties available with polymers in comparison to traditional silicon based microfabrication. In this Special Issue, we aim to highlight some of the recent application of polymers in MEMS, microfluidics and smart materials applications, as well as unique fabrication methods that integrate electrical and mechanical functionality with flexible, stretchable, biocompatible, or disposable devices. Topics of particular interest include, but are not limited to, micromanufacturing of polymer based sensors and actuators, microrobotic systems, novel fabrication processes and polymer materials, stretchable electronics, microinjection molded products, biocompatibility of polymer MEMS, polymer microfluidic systems, and additive manufacturing of MEMS.

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Guest Editor





Editor-in-Chief

Message from the Editor-in-Chief

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